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<b>APPLICANTS</b>  Ki Hwan Park, Suwon-Si, KOREA, REPUBLIC OF;  Jong Kook Song, Suwon-Si, KOREA, REPUBLIC OF; Mo Hyun Cho, Suwon-si, KOREA, REPUBLIC OF; Sung-Ho Cho, Hyasung-Kun, KOREA, REPUBLIC OF; Sun Jae Lee, Suwon-Si, KOREA, REPUBLIC OF; Pyung Ho Lim, Osan-Si, KOREA, REPUBLIC OF; Dong Wook Cho, Dong-Gu, KOREA, REPUBLIC OF;					
<b>** CONTINUING DATA *****</b> <i>None ZE</i>					
<b>** FOREIGN APPLICATIONS *****</b> REPUBLIC OF KOREA 03-75573 10/28/2003 <i>ZE</i>					
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 05/25/2004</b>					
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Allowance Verified and <i>ZE</i> Acknowledged Examiner's Signature Initials		STATE OR  COUNTRY KOREA, REPUBLIC OF	SHEETS  DRAWING 8	TOTAL  CLAIMS 38	INDEPENDENT  CLAIMS 4
<b>ADDRESS</b> Anthony P. Onello, Jr. MILLS & ONELLO LLP Suite 605 Eleven Beacon Street Boston , MA 02108					
<b>TITLE</b> System for rinsing and drying semiconductor substrates and method therefor					